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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Art Unit: 2815  
Examiner: Mr. Joseph H. Nguyen

In re PATENT APPLICATION of:

Applicant : Takashi NOGUCHI )  
Serial No. : 10/822,691 )  
Filed : April 13, 2004 )  
For : HEAT RADIATION STRUCTURE )  
OF SEMICONDUCTOR DEVICE, )  
AND MANUFACTURING )  
METHOD THEREOF )  
Atty Ref. : OKI 419 )

**AMENDMENT  
AFTER FINAL  
REJECTION**

March 6, 2006

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450  
Attn: Box AF

OK to enter TN 03/17/06

Sir:

This is responsive to the Office Action of December 5, 2005, the period for reply to which has been set to expire on March 5, 2006 (a Sunday, and thus on the following Monday, March 6, 2006).

A fee of \$ None is being submitted concurrently. Should this remittance be accidentally missing, however, or should any additional fees be needed (including extension of time fees, since Applicant hereby provisionally petitions for any extensions that may be deemed necessary to avoid abandonment), the Director may charge such fees to our Deposit Account number 18-0002.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.

FEE ENCLOSED: \$  
Please charge any further  
fee to our Deposit Account  
No. 18-0002